ABSTRACT

Disclosed herein is a wafer carrier locking device. The wafer carrier locking device includes a wafer carrier seated thereon a plurality of wafers. A main equipment executes a semiconductor manufacturing process, which is a wafer cleaning process, a wafer etching process, etc., when the wafers seated on the wafer carrier are fed to the main equipment by a multi-joint robot. An auxiliary equipment includes a carrier sensor to detect a seated state of the wafer carrier relative to a base member, a wafer sensor to detect a number and positions of the wafers seated on the wafer carrier, when the wafer carrier is seated on the base member, and the base member having a plate shape. In this case, a plurality of positioning blocks are provided at predetermined positions of the base member to allow the wafer carrier to be seated at a desired position on the base member. A locking unit is provided at a front portion of the base member to prevent the wafer carrier from being undesirably moved, when the wafer carrier is seated on the base member during the semiconductor manufacturing process of the main equipment. The wafer locking device of this invention prevents a wafer from being broken or damaged due to carelessness of a worker, and prevents a waste of resources due to the damaged wafer, and enhances productivity.